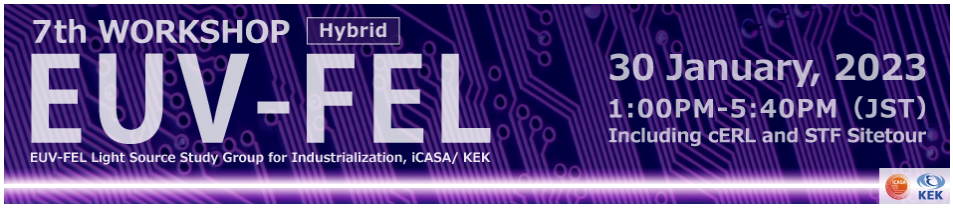

Contribution ID: **3** Type: **not specified**

Present state of the EUV-FEL light source for future lithography

Monday, 30 January 2023 14:45 (35 minutes)

Presenter: NORIO NAKAMURA (KEK)